IN THE CLAIMS:

Please amend Claims 1-29 as follows:

1. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

2. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure of 1×10^2 to 1×10^5 Pa; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

3. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the anode or the cathode.

4. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

5. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

ejecting a solution containing a light-emitting body composition from the below toward an anode or a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode at from room temperature to 200 °C; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

6. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

setting up an anode or a cathode in a range of 0° to 30° relative to a horizontal plane; ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode or the cathode.

7. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

setting up an anode or a cathode in a range of 0° to 30° relative to a horizontal plane;
ejecting a solution containing a light-emitting body composition from the below under a
pressure lower than atmosphere pressure; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate.

8. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

setting up an anode or a cathode in a range of 0° to 30° relative to a horizontal plane; ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

9. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

setting up an anode or a cathode in a range of 0° to 30° relative to a horizontal plane;

ejecting a solution containing a light-emitting body composition from the below under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode or the cathode at from room temperature to 200 °C; and

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode or the cathode.

10. (Currently Amended) A fabrication method of a light-emitting device is characterized by comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode provided on a substrate under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

11. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the anode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

12. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

13. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward an anode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the anode or the cathode by previously heating the anode at from room temperature to 200 °C;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the anode; and

forming a cathode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of a light emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

14. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 10 to 13,

wherein the fabrication method of the light-emitting device is characterized in that each of the formations of the thin film having at least one layer structuring the light-emitting body and

the cathode is performed in a deposition apparatus in a multi-chamber scheme without a release to the air.

15. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 10 to 13,

wherein the fabrication method of the light-emitting device is characterized in that each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in an in-line scheme without a release to the air.

16. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode provided on a substrate under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the cathode; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of a thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

17. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

forming a thin film having at least one layer structuring a light-emitting body by depositing the light-emitting body composition on the cathode and volatilizing a solvent in the solution in a duration before the solution arrives at the substrate; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of a light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

18. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the cathode by previously heating the cathode;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the cathode; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of at the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

19. (Currently Amended) A fabrication method of a light-emitting device comprising the steps of:

ejecting a solution containing a light-emitting body composition toward a cathode under a pressure lower than atmosphere pressure;

commencing to volatilize a solvent in the solution simultaneously with an arrival thereof at the cathode by previously heating the cathode at from room temperature to 200 °C;

forming a thin film having at least one layer structuring a light-emitting body by depositing a remaining of the light-emitting body composition on the cathode; and

forming an anode on the light-emitting body by a sputter method or an evaporation method after forming the thin film of the light-emitting body composition,

wherein the fabrication method of the light-emitting device is further characterized in that the formation of the thin film having at least one layer structuring the light-emitting body is performed by setting up the substrate with a substrate surface in a range of 0° to 30° relative to a horizontal plane, and by ejecting the solution containing the light-emitting body composition from the below of the substrate surface.

20. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 16 to 19,

wherein the fabrication method of a light-emitting device is characterized in that each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in a multi-chamber scheme without a release to the air.

21. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 16 to 19,

wherein the fabrication method of the light-emitting device is characterized in that each of the formations of the thin film having at least one layer structuring the light-emitting body and the cathode is performed in a deposition apparatus in an in-line scheme without a release to the air.

22. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light-emitting device is characterized in that under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1×10^3 to 1×10^5 Pa.

23. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light-emitting device is characterized in that under the pressure lower than atmosphere pressure is in an inert gas atmosphere at 1×10^2 to 1×10^5 Pa.

24. (Currently amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light emitting device is characterized in that the light-emitting body composition is intermittently deposited to form a thin film.

25. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light emitting device is characterized in that the light-emitting body composition is continuously deposited to form a thin film.

26. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light emitting device is characterized in that the solution containing the light-emitting body composition is ejected through a single or a plurality of nozzles.

27. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light emitting device is characterized in that the light-emitting body composition is at least one material selected from the group consisting of a hole injection material, a hole transport material, a luminescent material, an electron transport material, an electron injection material, a hole blocking material or and an electron blocking material.

28. (Currently Amended) A fabrication method of a light-emitting device according to any one of claims 1, 3 to 13 and 16 to 19,

wherein the fabrication method of the light-emitting device is characterized in that the thin film having at least one layer structuring the light-emitting body is a thin film to function as a layer selected from a luminescent layer, a hole injection layer, a hole transport layer, a hole

blocking layer, an electron injection layer, an electron transport layer or and an electron blocking layer.

29. (Currently Amended) A light-emitting device is characterized in that the light-emitting device is An electronic appliance comprising the light-emitting device fabricated by a method according to any one of claims 1 to 13 and 16 to 19.